

CLAIMS

1. (Amended) A ceramic heater for heating a semiconductor wafer comprising a ceramic substrate in a disc form and a resistance heating element formed on the surface of said ceramic substrate or inside said ceramic substrate,
5 wherein: said ceramic heater is equipped with:
a temperature-measuring means measuring the temperature of said ceramic substrate or an object to be heated;
10 a control unit supplying electric power to said heating element;
a memory unit memorizing the temperature data measured by said temperature-measuring means; and
an operation unit calculating electric power data required
15 for said heating element from said temperature data,
said ceramic heater being constituted such that said heating element is divided into at least 2 or more circuits and different electric power is supplied to each of the circuits based on the calculated electric power data.
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2. (Amended) A ceramic heater for heating a semiconductor wafer comprising a ceramic substrate in a disc form and a resistance heating element formed on the surface of said ceramic substrate or inside said ceramic substrate,
25 wherein: said ceramic heater is equipped with:
a temperature-measuring means measuring the temperature of said ceramic substrate or an object to be heated;
a power source supplying electric power to said heating element;
30 a control unit controlling the power source;
a memory unit memorizing the temperature data measured by said temperature-measuring means; and
an operation unit calculating electric power data required
for said heating element from said temperature data;
35 said ceramic heater being constituted such that said

Amendment under article 34 36

heating element is divided into at least 2 or more circuits and different electric power is supplied to each of the circuits based on the calculated electric power data.

Sub.

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~~3. (Amended) The ceramic heater for heating a semiconductor wafer according to any of claim 1 or 2,~~

~~wherein said temperature-measuring means is a temperature-measuring element.~~

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~~4. (Amended) The ceramic heater for heating a semiconductor wafer according to any of claim 1 or 2,~~

~~wherein said temperature-measuring means is a thermoviewer.~~

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Add

A².